Appl. No. 10/519,175 Amdt. dated May 9, 2008

Amendment under 37 CFR 1.116 Expedited Procedure

Examining Group 2813

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

- 1-17. (canceled)
- 1 18. (previously presented) A method as in claim 24 wherein step (b) advances 2 curing of the thermosetting resin.
 - 19 and 20. (canceled)
- 21. (previously presented) A method as in claim 24 wherein the
 semiconductor device comprises an integrated circuit.
- 1 22. (previously presented) A method as in claim 24 wherein step (a) includes a 2 transfer molding process.
- 1 23. (previously presented) A method as in claim 24 wherein step (a) includes a potting process.
- 1 24. (previously presented) A method of making a semiconductor device comprising:
- (a) sealing the semiconductor device in a package by surrounding it with
 thermosetting resin and thermally curing the resin at a first temperature;
- 5 (b) baking the thermosetting resin at a second temperature not higher than the 6 first temperature:
- 7 (c) further baking the thermosetting resin at a third temperature higher than
- $8 \quad \text{ the first temperature, wherein the third temperature is between about 220 °C and about 260 °C;} \\$
- 9 and

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- (d) inspecting the semiconductor device.
- 25. (previously presented) A method as in claim 24 wherein a conductive lead
 is adhesively affixed to a main surface of the semiconductor device.
- 26. (previously presented) A method as in claim 25 wherein the conductive
 lead is adhesively affixed to a peripheral portion of the main surface of the semiconductor
 device.
- 1 27. (previously presented) A method as in claim 26 wherein an electrode of 2 the semiconductor device is electrically connected to the conductive lead.

28-30. (canceled)